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(71)Applicant: SONY CORP

SUZUKI KEITA

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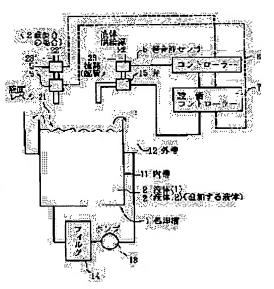
(72)Inventor:

## (54) LIQUID FLOW RATE CONTROL METHOD AND DEVICE THEREFOR

## (57)Abstract:

PROBLEM TO BE SOLVED: To provide a liquid flow rate control method and its device which attains precise control of a flow rate concerning a liquid obtained by mixing not less than two liquid while properly adjusting concn., etc., unnecessitates complicated adjustment and does not reduce the purity of the liquid.

SOLUTION: In this flow rate control method, ultrasonic sensors 5 and 5 are provided in flow passages 23 and 23' supplying liquid 2 and 2' into a processing tank 1 to detect a supplied liquid quantity by the ultrasonic sensors to compare the result between this detecting result and a previously stored supply quantity to control the quantity of a liquid to supply into the processing tank. In addition, the flow rate controller detecting and controlling the quantity of the liquid to supply into the processing tank is provided with a non-contact ultrasonic sensor with the liquid to monitor the liquid supply quantity into the processing tank by the sensor and provided with a controller 6 controlling the supplying quantity of the liquid within processing tank based on the data output of the sensor.



## **LEGAL STATUS**

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